

Notice of References Cited

Application/Control No.

10/724,278

Applicant(s)/Patent Under
Reexamination
LOVE ET AL.

Examiner

Michelle R. Connelly-Cushwa

Art Unit

2874

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U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
	B	US-			
	C	US-			
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

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*	O	DE 3516899 A1	11-1986	Germany	SCHWADERER et al.	G02B 06/24
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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Stockle et al., "High-quality near-field optical probes by tube etching", Applied Physics Letters, Volumn 75, Number 2, 12 July 1999, pages 160-162.
	V	
	W	
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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